

WEST Search History

DATE: Monday, February 05, 2007

Hide?	Set Name	Query	Hit Count
		<i>DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L14	L13 and l12	9
<input type="checkbox"/>	L13	134/94.1,95.1,95.3,137,140,902.ccls.	3987
<input type="checkbox"/>	L12	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	40
		<i>DB=EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L11	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	5
		<i>DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L10	(substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same ((scatter\$4 or spatter\$4) with (cup or chamber) with (clean\$3 or rins\$3 or wash\$3))	45
<input type="checkbox"/>	L9	L8 and ((substrate or semiconductor or wafer or workpiece or article) same ((hold\$3 or support\$3) with rotat\$3) same (scatter\$3 with (cup or chamber)))	14
<input type="checkbox"/>	L8	L7 or l6 or l5 or l4 or l3 or l2	2081
<input type="checkbox"/>	L7	(ebara corporation).as.	1267
<input type="checkbox"/>	L6	takeda-sachiko\$.in.	37
<input type="checkbox"/>	L5	inoue-yuki\$.in.	685
<input type="checkbox"/>	L4	ono-haruko\$.in.	18
<input type="checkbox"/>	L3	katakabe-ichiro\$.in.	76
<input type="checkbox"/>	L2	kajita-shinji\$.in.	35
		<i>DB=USPT; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L1	6265328.pn. or 6413436.pn.	2

END OF SEARCH HISTORY

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DB=USPT; PLUR=YES; OP=ADJ

☐ L18 L16 and l4

☐ L17 L16 and l2

☐ L16 (chamber or cup or bowl) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second or opposit) with (nozzle or spray\$3))

DB=EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ

☐ L15 (chamber or cup or bowl) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second or opposit) with (nozzle or spray\$3))

☐ L14 (chamber or cup) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second) with (nozzle or spray\$3))

☐ L13 (chamber or cup) same ((support\$3 or hold\$3) with rotat\$4) same ((clean\$3 or rins\$3 or w. bottom or second))

DB=JPAB; PLUR=YES; OP=ADJ

☐ L12 06106126

☐ L11 6106126

DB=EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ

☐ L10 ((chamber or cup) adj5 nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or

☐ L9 ((chamber or cup) with nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or

☐ L8 (chamber or cup) same nozzle same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or

DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ

☐ L7 L6 and l4

☐ L6 (chamber or cup) same nozzle same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or

☐ L5 L4 and l1

☐ L4 134/104.1;118/70.ccls.

☐ L3 L2 and l1

☐ L2 134/94.1,95.1,95.3,99.1,103.2,104.1,137,140,151,198,199,902,22.1,22.18,34,36;118/52,70

DB=USPT; PLUR=YES; OP=ADJ

☐ L1 ((chamber or cup) with nozzle) same ((support\$3 or hold\$3) with rotat\$4) same (clean\$3 or

END OF SEARCH HISTORY